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PATENT
DOCKET NO.: 29273/502

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS : Hajime KAWANO, et al.
SERIAL NO. : 09/315,988
FILED : 21 May 1999
FOR : ELECTRON BEAM LITHOGRAPHY SYSTEM
Patent No. : **6,828,573 B1** Issued 07 December 2004

COMMISSIONER FOR PATENTS
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REQUEST FOR CERTIFICATE OF CORRECTION
PURSUANT TO 37 C.F.R. § 1.322

SIR:

It is respectfully requested that the enclosed certificate of correction be issued for the above Patent under authority of 35 USC §354.

The change represents correction of an error which occurred during printing of the patent and was not the fault of the applicants. Therefore, no fee is required.

Respectfully submitted,

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Dated: 03 May 2005

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UNITED STATES PATENT AND TRADEMARK OFFICE CERTIFICATE OF CORRECTION

PATENT NO. : US 6,828,573 B1
DATED : 07 December 2004
INVENTOR(S) : Hajime KAWANO, et al.

Page 1 of 1

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

<u>Column</u>	<u>Line</u>	
12	19	Change "N _a /2." to --N _s /2.--.

MAILING ADDRESS OF SENDER:

Patent No.: 6,828,573 B1

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